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CONFIRMATION NO. 1952

SERIAL NUMBER 09/964,648	FILING DATE 09/28/2001 RULE	С	LASS 438			D		ATTORNEY OCKET NO. 862.C2397
APPLICANTS Keiji Yoshimu	ra, Tochigi, JAPAN;							
JAPAN 2001/	E	***** GRANTE	ED.					
Foreign Priority claimed 35 USC 119 (a-d) conditions yes no no Met after Allowance Verified and Acknowledged Acknowledged Acknowledged			STATE OR COUNTRY JAPAN	SHEETS DRAWING 15		TOTAL CLAIMS 27		INDEPENDENT CLAIMS 10
ADDRESS 05514				•				
TITLE Exposure apparatus, semiconductor device manufacturing method, exposure apparatus maintenance method and semiconductor manufacturing factory								
, ·					All Fees			
					1.16 Fees (Filing)			
RECEIVED No	ES: Authority has been g to charge/cr	aper OSIT ACCOUNT		1.17 Fees (Processing Ext. of time)				
1396 No	for following			1.18 Fees (Issue)				
				Other				
				Credit				